

ABSTRACT OF THE DISCLOSURE

There is disclosed a piezoelectric/electrostrictive device made of piezoelectric/electrostrictive film which includes: a substrate section; and an operation section disposed on the substrate section and constituted of a piezoelectric/electrostrictive film and an electrode film and which operates by displacement of the operation section. The operation section comprises the piezoelectric/electrostrictive films and electrode films alternately laminated so that uppermost and lowermost layers form the electrode films, the operation and substrate sections are integrally fired, and the substrate section is constituted of a ceramic which contains a titanium element. For the piezoelectric/electrostrictive device made of piezoelectric/electrostrictive film, a residual stress after firing hardly exists, therefore larger displacement is obtained with the same driving voltage, response speed is higher, and generation force is larger.